

## Electronic Patent Application Fee Transmittal

<b>Application Number:</b>	10689617			
<b>Filing Date:</b>	22-Oct-2003			
<b>Title of Invention:</b>	Method for cleaning plasma etching apparatus, method for plasma etching, and method for manufacturing semiconductor device			
<b>First Named Inventor/Applicant Name:</b>	Satoru Okamoto			
<b>Filer:</b>	Diana DiBerardino/Arlene Yates			
<b>Attorney Docket Number:</b>	12732-170001			
Filed as Large Entity				
<div style="display: flex; justify-content: space-between;"> <span>Utility</span> <span><b>Filing Fees</b></span> </div>				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Basic Filing:</b>				
<b>Pages:</b>				
<b>Claims:</b>				
<b>Miscellaneous-Filing:</b>				
<b>Petition:</b>				
<b>Patent-Appeals-and-Interference:</b>				
Notice of appeal	1401	1	510	510
<b>Post-Allowance-and-Post-Issuance:</b>				
<b>Extension-of-Time:</b>				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Total in USD (\$)				510